

Stundenplan für Master Mechatronic
Wintersemester, 1. Fachsemester - nach der neuen FPO 2023

	Montag	Dienstag	Mittwoch	Donnerstag	Freitag
08:00-10:00	Communication and Information Security 1, V	Microelectronic Sensors, Ü	Electrical Engineering, VÜ	Introduction to Programming, V	Introduction to Programming, Ü
		Data Communications Technology 1, V			
10:00-12:00		Data Communications Technology 1, Ü	Automation Technologies, V	Linear Control – Fundamental of Control, VÜ	Automation Technologies, Ü
		Introduction to Machine Learning, V			
	Communication and Information Security 1, Ü		Introduction to Machine Learning, Ü	Introduction to Machine Learning, Ü	
				Numerische Fluidodynamik, V	
12:00-14:00		Engineering Mechanics, VÜ			Mechatronic Systems, V
					Computational Imaging, Ü
14:00-16:00	Condition Monitoring, V	Engineering Design I, V			Computational Imaging, Ü
		Introduction to Compressive Sensing, V		Introduction to Machine Learning, Ü	
16:00-18:00	Condition Monitoring, Ü	Introduction to Compressive Sensing, Ü		Mechatronic Systems, Ü	
	Microelectronic Sensors, V				
18:00-20:00		Computational Imaging, V			

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Stundenplan für Master Mechatronic
Wintersemester, 3. Fachsemester - nach der neuen FPO 2023

	Montag	Dienstag	Mittwoch	Donnerstag	Freitag
08:00-10:00	Communication and Information Security 1, V	Microelectronic Sensors, Ü			Embedded Control, Ü
		Data Communications Technology 1, V			
10:00-12:00		Data Communications Technology 1, Ü	Deep Learning, Ü	Numerische Fluidodynamik, V	
		Introduction to Machine Learning, V	Embedded Control, Ü	Introduction to Machine Learning, Ü	
	Communication and Information Security 1, Ü		Introduction to Machine Learning, Ü		
	Neuronale Netze und Fuzzy-Systeme, V				
12:00-14:00				Embedded Control, V	Mechatronic Systems, V
				Deep Learning, V	Computational Imaging, Ü
14:00-16:00	Condition Monitoring, V	Introduction to Compressive Sensing, V		Introduction to Machine Learning, Ü	Computational Imaging, Ü
	Deep Learning, Ü				
16:00-18:00	Condition Monitoring, Ü	Introduction to Compressive Sensing, Ü		Mechatronic Systems, Ü	
	Microelectronic Sensors, V				
		Embedded Control, Ü			
18:00-20:00		Computational Imaging, V			

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